	Application No.	Applicant(s)	
Nation of Allowability	10/766,209	TAKAISHI, MASARU	
Notice of Allowability	Examiner	Art Unit	
<u> </u>	PHUC T DANG	2818	
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.			
1. X This communication is responsive to <u>January 29, 2004</u> .			
2. The allowed claim(s) is/are <u>1-8</u> .			
3. The drawings filed on 29 January 2004 are accepted by the Examiner.			
 4. Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b)			
 Attachment(s) 1. ☑ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☑ Information Disclosure Statements (PTO-1449 or PTO/SB/O Paper No./Mail Date 042704 4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material 	8. ⊠ Examiner's Stateme 9. □ Other	(PTO-413), te ment/Comment ent of Reasons for Allo	owance
PHUCT DANG Janganer			
PHUCT DANG Saughur PRIMARY EXAMINER			

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DETAILED ACTION

Examiner's Statement of Reasons for Allowance

- 1. Claims 1-8 are allowed.
- 2. The following is an examiner's statement of reasons for allowance:

With respect to claim 1, the prior art of record, taken alone or in combination, fails to teach or reasonably suggests a method for manufacturing a semiconductor device having a semiconductor substrate with a contact hole filled by an aluminum-containing thin film, comprising a step of forming an aluminum-containing thin film on the surface of the semiconductor substrate after completing the step of removing the part of the silicon-containing thin film, in combination with the rest of the limitations of claim 1.

- 3. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submission should be clearly labeled "Comments on Statement of Reasons for Allowance".
- 4. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Phuc T. Dang whose telephone number is (571) 272-1776. The examiner can normally be reached on 8:00 am-5:00 pm.
- 5. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, David C. Nelms can be reached on (571) 272-1787. The fax phone numbers for the organization where this application or proceeding is assigned are 703-872-9306 for regular communications and After Final communications.

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6. Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 703-308-0956.

Langflow

PD

Phuc T. Dang

Primary Examiner

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